



ISC Audits & Reviews SC Summary (May 2017)

Doc.	Title	Results
4689;	Revision to SEMI M55-0315, Specification for Polished Monocrystalline Silicon Carbide Wafers;	Passed
5549A;	Revision to SEMI E30, Generic Model for Communications and Control of Manufacturing Equipment (GEM) with title change to: Specification for the Generic Model for Communications and Control of Manufacturing Equipment (GEM);	Passed
5738;	Revision to SEMI E87.1-0707 Specification for SECS-II Protocol for Carrier Management (CMS);	Passed
5840;	New Standard: Guide for Calibration of PV Module UV Test Chambers;	Passed
5843;	Revision of SEMI PV22-0716, Specification for Silicon Wafers for Use in Photovoltaic Solar Cells;	Passed
5926;	New Standard: Test Method for Bending Property of Flexible Thin Film PV Modules;	Passed
5943;	Revision to SEMI E49.2-1104: Guideline For The Qualification Of Polymer Assemblies Used In Ultrapure Water And Liquid Chemical Systems In Semiconductor Process Equipment with title change to Guide For The Qualification Of Polymer Assemblies Used For Liquid Chemical Systems In Semiconductor Equipment;	Passed
5974;	New Auxiliary Information: 450mm PIC Interoperability;	Passed
5975;	Reapproval of SEMI M45-1110 Specification for 300mm wafer shipping System;	Passed
6016;	New Standard: Test Method for Exposure Durability of PV Cells to Acetic Acid Vapor;	Passed
6026A	Line Item Revision to SEMI E109-1110, Specification for Reticle and Pod Management (RPMS)	
6026A-LI1;	To correct invalid references in the current published version of the standard and make revision to various sections.;	Passed
6051A	Line Item Revisions to SEMI E111-1213, Mechanical Specification for a 150 mm Reticle SMIF Pod (Rsp150) Used to Transport and Store a 6 Inch Reticle	
6051A-LI1;	Correct the title of SEMI E111 from "Mechanical Specification for a 150 mm Reticle SMIF Pod (Rsp150) Used to Transport and Store a 6 Inch Reticle" to "Specification for a 150 mm Reticle SMIF Pod (RSP150) Used to Transport and Store a 6 Inch Reticle";	Passed
6051A-LI2;	Correct definitions to conform to the Style Manual as indicated;	Passed
6052A	Line Item Revision to SEMI E112-1213, Mechanical Specification for a 150 mm Multiple Reticle SMIF Pod (MRSP150) Used to Transport and Store Multiple 6 Inch Reticles	
6052A-LI1;	Correct the title of SEMI E112 from "Mechanical Specification for a 150 mm Multiple Reticle SMIF Pod (MRSP150) Used to Transport and Store Multiple 6 Inch Reticles" to "Specification for a 150 mm Multiple Reticle SMIF Pod (MRSP150) Used to Transport and Store Multiple 6 Inch Reticles";	Passed



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6052A-LI2;	Correct definitions to conform to the Style Manual as indicated;	Passed
6054A	Line Item Revisions to SEMI E18-0211, Guide for Temperature Specifications of the Mass Flow Controller	
6054A-LI1;	Modify Terminology Section 4.1.9;	Passed
6054A-LI2;	Modify Terminology Section 4.1.10.1;	Passed
6054A-LI3;	Modify Terminology Section 4.1.10.2;	Passed
6054A-LI4;	Modify Terminology Section 4.1.10.3;	Passed
6055A	Line Item Revision to SEMI E27-0611, Guide for Mass Flow Controller and Mass Flow Meter Linearity	
6055A-LI1;	Change “shall” to “should” throughout per Style Manual;	Passed
6064A	Line Item Revision to SEMI E121-0305, Guide for Style and Usage of XML for Semiconductor Manufacturing Applications	
6064A-LI1;	According to SEMI Regulations, a guide cannot have requirements. This ballot is to correct the usage of terms “shall” and “must” to a statement appropriate for a Guide and also to update any invalid references within the document.;	Passed
6066A	Line Item Revision to SEMI E130, Specification for Prober Specific Equipment Model for 300 mm Environment (PSEM300) and SEMI E130.1, Specification for SECS-II Protocol for Prober Specific Equipment Model for 300 mm Environment (PSEM300)	
6066A-LI1;	Remove from SEMI E130 the reference to the “Data Types” section in Standard E30 as this section no longer exists.;	Passed
6066A-LI2;	SEMI E130.1 Specification is balloted for reapproval with no changes.;	Failed
6067A;	Reapproval for SEMI E54.10-0600 (Reapproved 1111) Specification for Sensor/Actuator Network Specific Device Model for an in Situ Particle Monitor Device;	Passed
6068A	Line Item Revision to SEMI E116-0707E, Specification for Equipment Performance Tracking and SEMI E116.1-0707, Specification for SECS-II Protocol for Equipment Performance Tracking (EPT)	
6068A-LI1;	Remove the text “an Appendix of” related to E30 because this section does not exist in the current version and is expected to be renamed “Related Information” in a future version; and remove the “Provisional” name from the SEMI 101 reference. ;	Passed
6068A-LI2;	Reapprove SEMI E116.1 as published.;	Failed
6086;	Revision to SEMI F75-1102, Guide For Quality Monitoring Of Ultrapure Water Used In Semiconductor Manufacturing;	Passed
6088	Line Item Revision to SEMI PV35-0215: Specification for Horizontal Communication between Equipment for Photovoltaic Fabrication System, including its subordinate document PV35.1-0215 with designation letter change and non-conforming title change	
6088-LI1;	Change designation of SEMI PV35 from “PV” to “A”;	Passed
6088-LI2;	Correct non-conforming title of SEMI PV35.1;	Passed
6088-LI3;	Revise the length of data block;	Passed
6088-LI4;	Correct the abbreviation of data block in PV35;	Passed



Doc.	Title	Results
6088-LI5;	Release assigned STD_IDs which are not used in PV35;	Passed
6088-LI6;	Improve expressions which indicate the length of 'Line Information' or 'Track Information' in Data Block of PV35.1;	Passed
6089	Line Item Revision to "SEMI E170-0416: Specification For Secured Foundation Of Recipe Management System (SFORMS)", "SEMI E170.1-0416: Specification For SECS-II Protocol For Secured Foundation Of Recipe Management System" and "SEMI E5-0813: SEMI Equipment Communications Standard 2 Message Content (SECS-II)" with title change	
6089-LI1;	Revise the Message Mapping in SEMI E170.1 with some Parameter Changes in SEMI E170, and Add SECS message definitions in SEMI E5.;	Passed
6089-LI2;	Change nonconforming title of SEMI E5;	Passed
6090	Line Item Revision to SEMI E91-0600 (Reapproved 1109), Specification For Prober Specific Equipment Model (PSEM)	
6090-LI1;	Reflect related SEMI E30 revisions;	Passed
6090-LI2;	Delete "provisional" related expressions;	Passed
6090-LI3;	Correct some technical errors and reference error;	Passed
6091	Line Item Revision to SEMI E174-1116: Specification For Wafer Job Management (WJM)	
6091-LI1;	Replace old mnemonic "WFJOBReport" with new mnemonic "WJReport".;	Passed
6091-LI2;	Align terminologies and wordings with SEMI E133;	Passed
6091-LI3;	Improve Abbreviations and Acronyms.;	Passed
6091-LI4;	Improve SEMI Standards references.;	Passed
6091-LI5;	Move figure to appropriate section and add explanations on WJ and WFJ.;	Passed
6091-LI6;	Move figures to appropriate sections and improve explanations of PJG and EXG.;	Passed
6091-LI7;	Make WJFlow optional and improve explanations;	Passed
6091-LI8;	Add explanations to figures in Potential Use Cases;	Passed
6091-LI9;	Add Response Information to WFJEvent and WJReport services.;	Passed
6091-LI10;	Improve expressions and explanations.;	Passed
6098;	Reapproval of SEMI S3-1211, Safety Guideline for Process Liquid Heating Systems ;	Passed
6101	Line Item Revision of SEMI D31-0914, Definition of Measurement Index (DSEMU) for Luminance Mura in FPD Image Quality Inspection, with title change to: Guide for Definition of Measurement Index (DSEMU) for Luminance Mura in FPD Image Quality Inspection.	
6101-LI1;	Correct title and concomitant text of SEMI D31;	Passed
6105;	Revision to SEMI F51-1115, Guide for Elastometric Sealing Technology;	Passed
6108;	Reapproval of SEMI F20-0706E (Reapproved 0611), Specification for 316L Stainless Steel Bar, Forgings, Extruded Shapes, Plate, and Tubing for Components Used in General Purpose, High	Passed



Doc.	Title	Results
	Purity and Ultra-High Purity Semiconductor Manufacturing Applications ;	
6115;	Reapproval for SEMI E163-0212, Guide for the Handling of Reticles and Other Extremely Electrostatic Sensitive (EES) Items within Specially Designated Areas;	Passed
6119;	Revision to SEMI E17-1011, Guide for Mass Flow Controller Transient Characteristics Tests with Title Change to Test Method for Measurement of Mass Flow Controller Transient Characteristics;	Passed
6120;	Reapproval of SEMI E137-0705 (Reapproved 1111), Guide for Final Assembly, Packaging, Transportation, Unpacking, and Relocation of Semiconductor Manufacturing Equipment;	Passed
6121;	Reapproval of SEMI E67-1011, Test Method for Determining Reliability of Mass Flow Controller ;	Passed
6122;	Reapproval of SEMI F78-0611, Practice for Gas Tungsten Arc (GTA) Welding of Fluid Distribution Systems in Semiconductor Manufacturing Applications;	Passed
6123;	Reapproval of SEMI F81-0611, Specification for Visual Inspection and Acceptance of Gas Tungsten Arc (GTA) Welds in Fluid Distribution Systems in Semiconductor Manufacturing Applications;	Passed
6126	Line Item Revision to Correct the Title of SEMI F24-0697 (Reapproved 0712), Particle Specification for Grade 10/0.2 Inert Specialty Gases	
6126-LI1;	Correct nonconforming title per SEMI Standards Procedure Manual;	Passed
6127	Line Item Revision to Correct the Title of SEMI F25-0697 (Reapproved 0712), Particle Specification for Grade 10/0.2 Oxidant Specialty Gases	Passed
6127-LI1;	Correct nonconforming title per SEMI Standards Procedure Manual;	Passed
6128	Line Item Revision to Correct the Title of SEMI F26-0697 (Reapproved 0712), Particle Specification for Grade 10/0.2 Toxic Specialty Gases	
6128-LI1;	Correct nonconforming title per SEMI Standards Procedure Manual;	Passed
6129;	Revision to SEMI F61-0301 (Reapproved 0309) Guide for Ultrapure Water System Used in Semiconductor Processing, with title change to: Guide to Design and Operation of a Semiconductor Ultrapure Water System;	Passed
6130;	Reapproval of SEMI E84-1109: Specification for Enhanced Carrier Handoff Parallel I/O Interface;	Passed
6137;	Reapproval of SEMI C55-1104 (Reapproved 0211), Specification for Liquid Carbon Dioxide (CO2) Used in Near Critical, Critical and Supercritical Applications, >/ 99.99% Quality;	Passed
6138;	Reapproval of SEMI C3.27-1102 (Reapproved 1011), Specification for Boron Trifluoride (BF3) in Cylinders, 99.0% Quality;	Passed
6139;	Reapproval of SEMI C3.39-1011, Specification for Nitrogen Trifluoride (NF3), 99.98%;	Passed



Doc.	Title	Results
6140;	Reapproval of SEMI C3.2-0611, Specification for Arsine (AsH ₃) in Cylinders, 99.94% Quality;	Passed
6141;	Reapproval of SEMI C3.47-1011, Specification for Hydrogen Bromide (HBr), 99.98% Quality;	Passed
6142;	Reapproval of SEMI C3.55-1011, Specification for Silane (SiH ₄), Bulk, 99.994% Quality;	Passed
6143;	Reapproval of SEMI C3.40-1011, Specification for Carbon Tetrafluoride (CF ₄), 99.997% Quality;	Passed

Line Item (LI)

There were two abstentions that were tallied as reject.

Doc. 6066A Line Item 2 and 6068A Line Item 2 failed. All other documents passed and will be forwarded to Standards Publications for final processing.

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May 16, 2017